

Attorney's Docket No. 5649-842



1762
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Kang et al.

Serial No.: ~~09/655,208~~ 09/665 258

Filed: September 18, 2000

For: *Apparatus for Forming Thin Films and Methods for Forming Capacitors on Semiconductor Substrates Using the Same*

Date: February 8, 2001

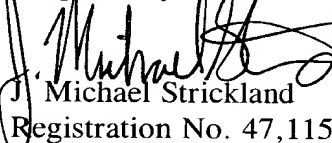
Commissioner for Patents
Washington, DC 20231

**INFORMATION DISCLOSURE STATEMENT
CITATION UNDER 37 C.F.R. § 1.97**

Sir:

Attached is a list of documents on form PTO-1449 together with a copy of each identified document. It is requested that these documents be considered by the Examiner and officially made of record in accordance with the provisions of 37 C.F.R. § 1.97 and Section 609 of the MPEP.

Respectfully submitted,

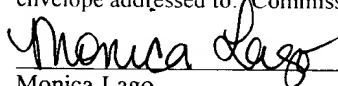

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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, Washington, DC 20231, on February 8, 2001.



Monica Lago

Date of Signature: February 8, 2001